

Notice of References Cited	Application/Control No. 10/002,953	Applicant(s)/Patent Under Reexamination FELTON ET AL.	
	Examiner Roberts Culbert	Art Unit 1763	Page 1 of 1

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*	B	US-6,555,417	04-2003	Spooner et al.	438/113
*	C	US-2002/0088988	07-2002	Silverbrook, Kia	257/99
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*	E	US-2003/0092229	05-2003	Silverbrook, Kia	438/200
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.